PIVOTAL SYSTEMS

Pivotal Introduces Sensor X™—An Unprecedented Atomic-Level Gas Composition Analysis Tool

SENSOR X OFFERS A MULTITUDE OF APPLICATIONS FOR REAL TIME MONITORING OF THE WAFER PROCESSING ENVIRONMENT

Pleasanton, CA.—March 23, 2007—Pivotal Systems Corporation today announced the launch of its Sensor X™ product, an unprecedented in situ atomic-level gas composition analysis tool. Sensor X is a remote plasma sensor for real-time species identification through optical emission spectroscopy (OES). The system attaches to any port on a vacuum chamber; at typical wafer processing pressures (e.g., below 5 torr), gases from the chamber quickly diffuse in and out of Sensor X's micro-cavity for real-time plasma-based OES analysis.

Unprecedented Atomic-Level Vision

The heart of Pivotal's advantage over traditionally available sensors is its ability to drive the gas within its micro-cavity to an atomic versus molecular emission spectrum. Sensor X achieves this through its proprietary chamber design and input power specifications to create a very high density plasma. With atomic emission, species identification is easier and signal to noise performance is better.

"Our customers are very excited about Sensor X because of the multitude of applications where it can deliver value immediately," said Chuck Borowski, Pivotal's Director of Product Marketing, "Low Exposed Area Etch End Point is a great example where current systems are failing the process and equipment engineers. With Sensor X, end point detection becomes very easy because we can excite key atomic species such as silicon, which is the very material being etched off the wafer during an oxide etch. As such, Sensor X provides a clear and valuable eye into the wafer processing environment."

About Pivotal Systems

Pivotal Systems Corporation provides best-in-class monitoring and process control technology for the semiconductor manufacturing industry. Pivotal's vision is to enable an order of magnitude increase in fab productivity and capital efficiency for current and future technology nodes. This vision is achieved through its real time in situ process monitoring and control solutions. Founded in 2003 and based in Pleasanton, California, the company is led by veterans from the semiconductor and high-tech industries. For more information about Pivotal, please visit www.pivotalsys.com, or send an email to info@pivotalsys.com.